



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koichiro KOMATSU et al.

Group Art Unit: 2877

Application No.: 09/481,503

Examiner: R. A. Rosenberger

Filed: January 12, 2000

Docket No.: 105173

For: SURFACE INSPECTION METHOD, SURFACE INSPECTION APPARATUS, AND
RECORDING MEDIUM AND DATA SIGNAL FOR PROVIDING SURFACE
INSPECTION PROGRAM

AMENDMENT

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

In reply to the November 6, 2002 Office Action, please amend the above-identified application as follows:

IN THE CLAIMS:

Please cancel claim 2 without prejudice to or disclaimer of the subject matter contained therein.

Please replace claims 1, 11 and 12 as follows:

B1
1. (Amended) A surface inspection method for inspecting a pattern formed at a surface of a test piece, comprising:

a first step in which a plurality of inspection conditions that are different from each other are set;

a second step in which light from the surface of the test piece is detected by irradiating illumination light onto the surface of the test piece under each of said plurality of inspection conditions;

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